



RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2851

00862.022246

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Kazunori IWAMOTO et al.

Application No.: 09/866,600

Filed: May 30, 2001

For: STAGE APPARATUS WHICH SUPPORTS
INTERFEROMETER, STAGE POSITION
MEASUREMENT METHOD, PROJECTION
EXPOSURE APPARATUS, PROJECTION
EXPOSURE APPARATUS MAINTENANCE
METHOD, SEMICONDUCTOR DEVICE
MANUFACTURING METHOD, AND
SEMICONDUCTOR MANUFACTURING FACTORY :

)
: Examiner: H. Nguyen
)
: Group Art Unit: 2851
)
: Confirmation No.: 4961
)
: October 8, 2003

Mail Stop AF

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION

Sir:

In response to the Official Action dated July 8, 2003, please amend the above-identified
application as follows:

10/09/2003 SS1TH1B1 00000041 09866600

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